

# JNTE 10

NOVEMBER 24-26, ECOLE POLYTECHNIQUE, PALAISEAU

## OPTICAL COUPLING OF SOI WAVEGUIDES AND III-V PHOTODETECTORS



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**Timo Aalto, Mikko Harjanne,  
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[http://vtt.fi/research/technology/micro\\_and\\_nanophotonics.jsp](http://vtt.fi/research/technology/micro_and_nanophotonics.jsp)

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**IMEC, Photonics Research Group**

<http://photonics.intec.ugent.be>



**ESA/ESTEC  
(ARTES 5)**



SEVENTH FRAMEWORK  
PROGRAMME

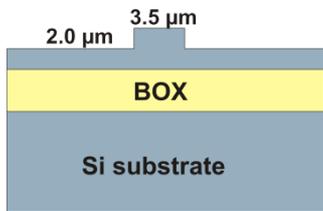


- **Background and motivation**
- **Coupling light from fiber to silicon waveguides**
  - Principle of grating couplers
- **Photodiode design**
  - Photodiode design for high speed
  - Prism coupling
  - Evanescent coupling
- **Fabrication**
  - Prism photodiode fabrication
  - Heterogeneous integration
- **Performance**
  - Prism photodiodes, discrete and integrated (OTUS)
  - Heterogeneously integrated photodiodes (BOOM)
- **Conclusion**

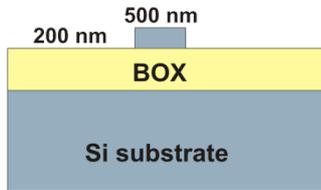
**SOI platform**

light wave  
guiding and  
processing  
(optics - interference)  
**CMOS technology**

SOI waveguides:

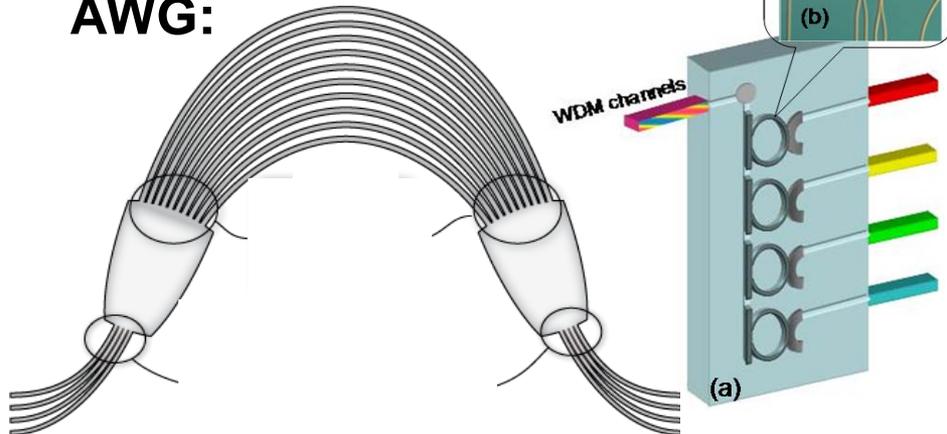


type "micro"



type "nano"

**AWG:**



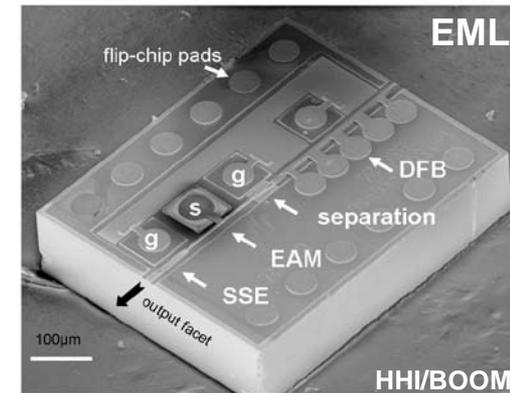
light detection,  
modulation  
and generation  
(applied  
Quantum Theory)

wavelength range: 1.3  $\mu\text{m}$  ... 1.5  $\mu\text{m}$   
(fibre based telecommunication)

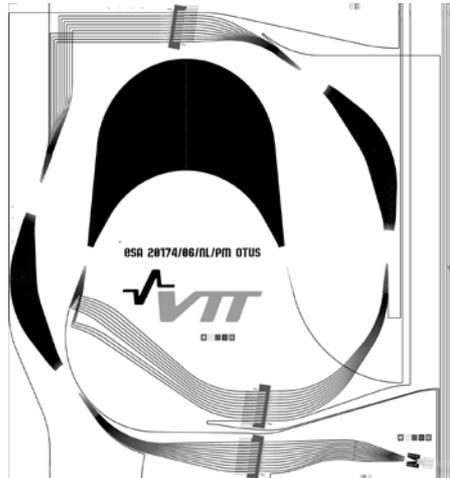
InP, InGaAsP,  
InAlGaAs  
InGaAs on InP

Waveguides,  
photodiodes,  
modulators: **Mach-Zehnder (MZI),**  
**electro-absorption (EAM),**  
**semiconductor amplifiers (SOA)**  
**lasers and integrated devices**

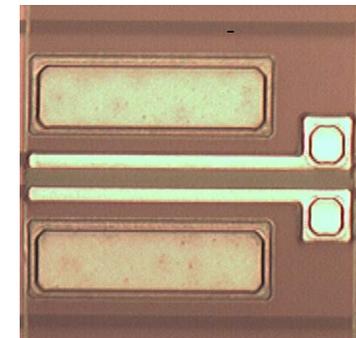
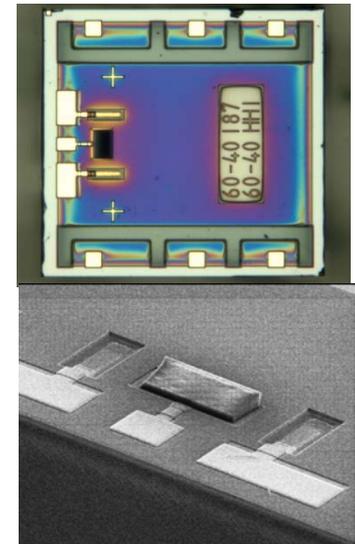
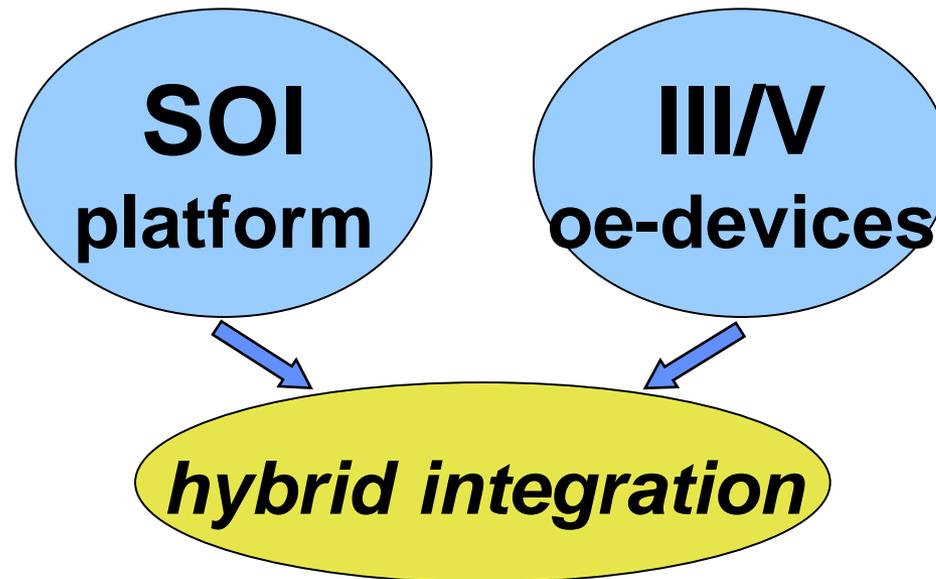
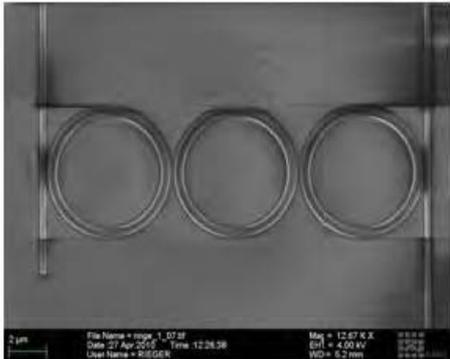
**III/V  
oe-devices**



“micro”-waveguides:



“nano”-waveguides:

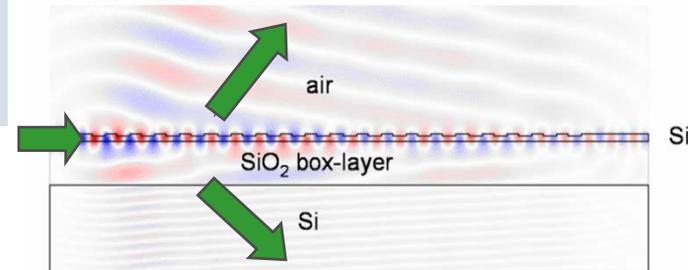
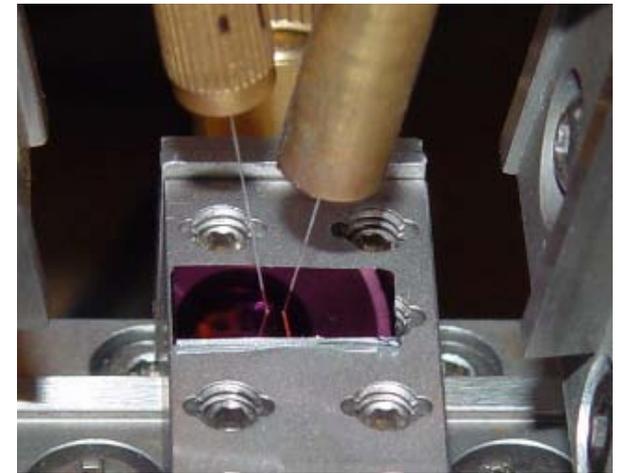
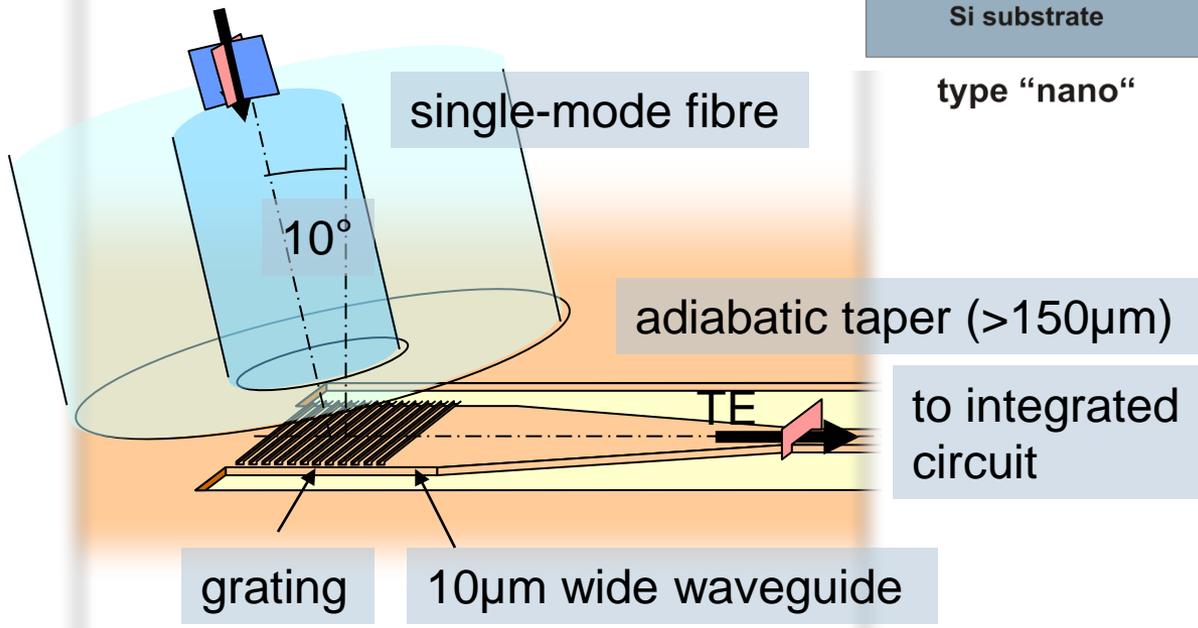


Integration, optical coupling → How?

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# Coupling light into Si "nano" waveguides

## Grating fiber couplers

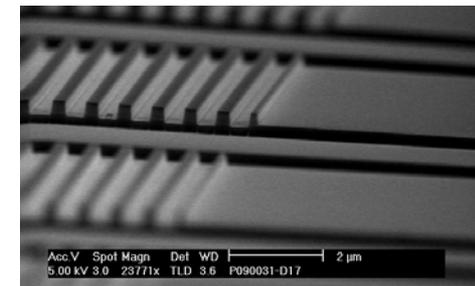


## Efficiency

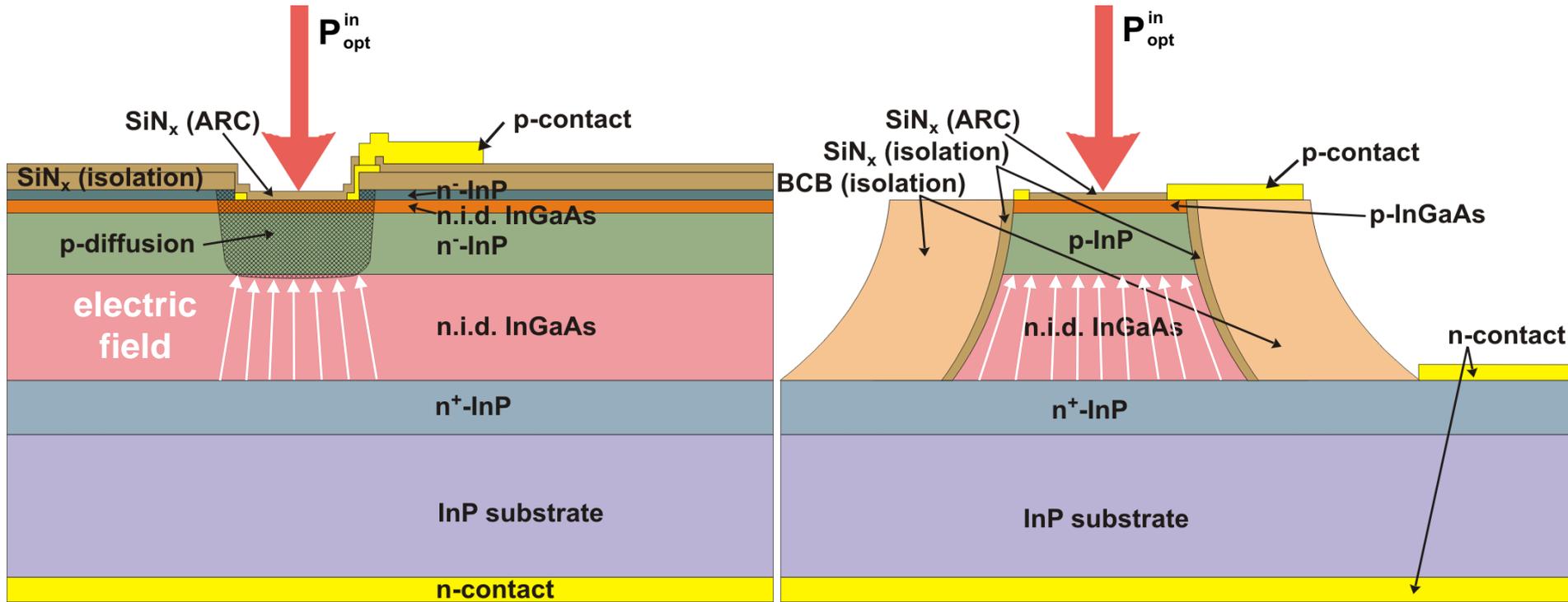
- Standard: 31 %
- With poly-silicon overlay: 68 %

D. Taillaert, JQE 7, p949 (2002)

D. Vermeulen, GFP09, PD1



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planar type

mesa type

# How to make a high-speed PD

Bandwidth is depending on:

(K. Kato,1993.)

- The time it takes a carrier to drift across the depletion region

$$f_t = \frac{3.5v}{\pi d}$$

$v$  = average speed holes and electrons  
 $d$  = thickness intrinsic layer

- The time it takes to charge and discharge the capacitance of the diode

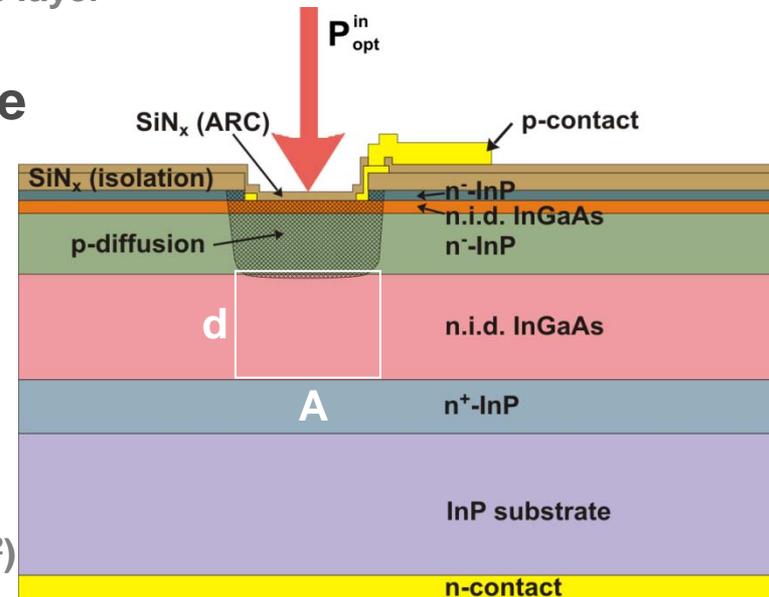
$$f_{RC} = \frac{1}{2\pi C(R_{load} + R_{contact})}$$

$C$  = capacitance  
 $R$  = resistance

$$C = \frac{\epsilon_0 \epsilon_r A}{d}$$

$$R = \frac{k}{A}$$

$A$  = area  
 $d$  = thickness intrinsic layer  
 $\epsilon_r$  = relative permittivity  
 $k$  = contact resistance (Ohm.m<sup>2</sup>)

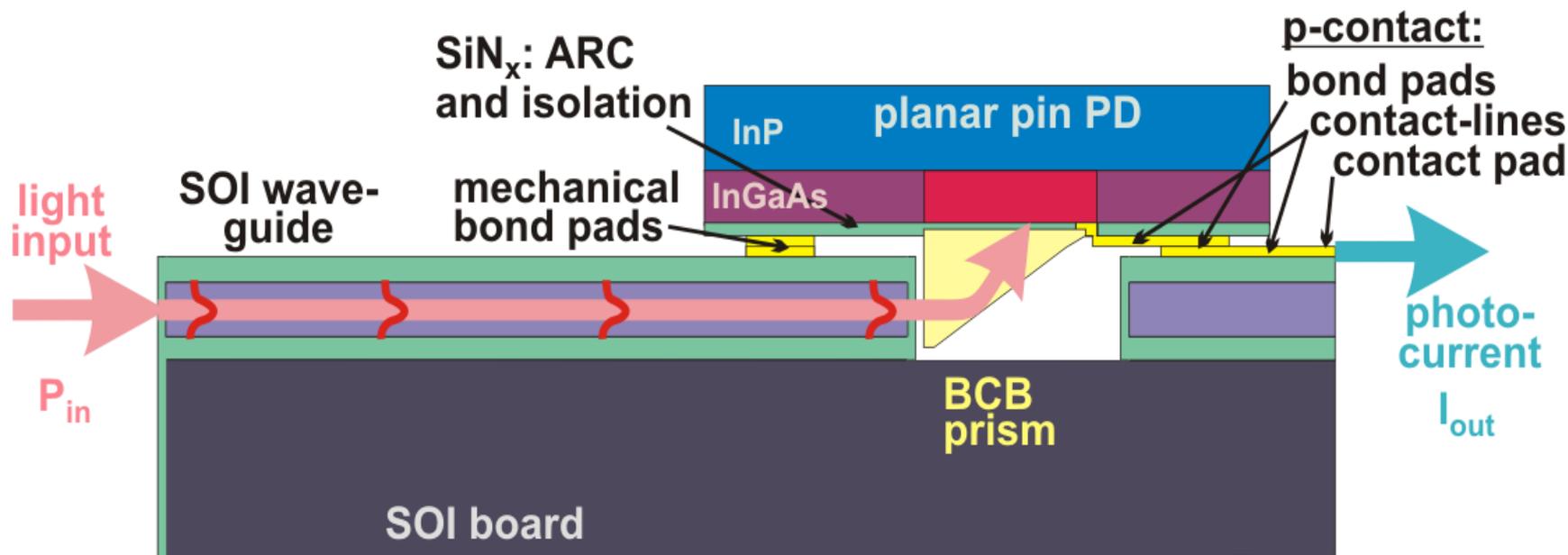


However:  $C$  is determined by active area *and* parasitics

Total 3-dB bandwidth:

$$\frac{1}{f_{3dB}^2} = \frac{1}{f_t^2} + \frac{1}{f_{RC}^2}$$

# OTUS PD: Integration and optical coupling



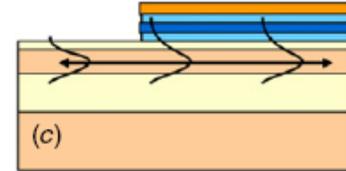
## Requirements:

- **Compatible architectures (fabrication, integration)**
- **Effective optical coupling (high responsivity)**
- **Suitable for 10 Gb/s operation**
- **Independent of polarization and wavelength**

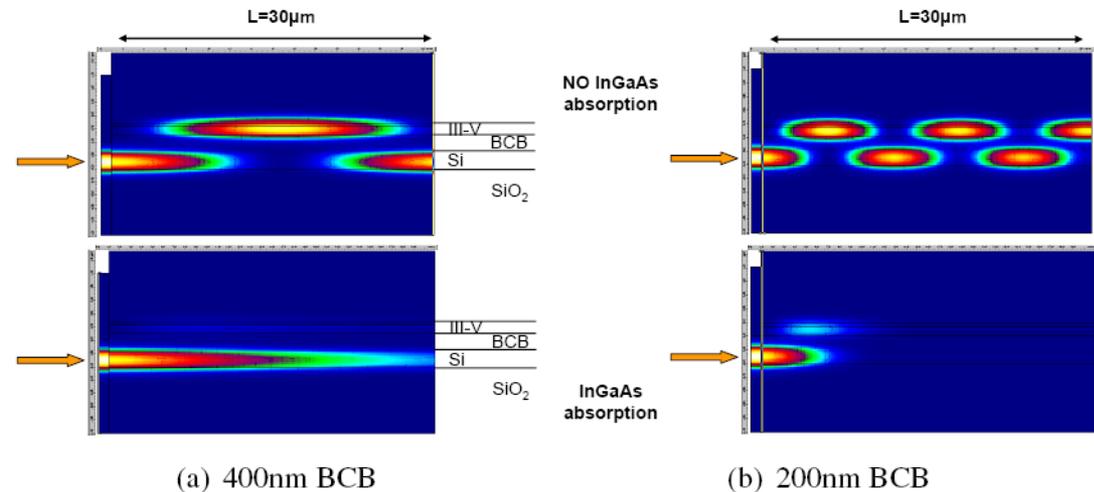
# Light coupling Si “nano” waveguides/III-V PDs

## Principle of evanescent coupling

- Coupled mode theory: power transfer from Si waveguide into III-V absorption layer
- For large & fast power transfer
  - Similar phase velocity  $\rightarrow$  small phase mismatch
  - Large mode overlap  $\rightarrow$  thin bonding layer
- Power transferred into the III-V layer is absorbed



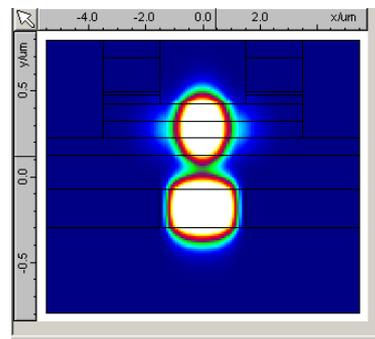
Example evanescently coupled PD:  
Power transfer from silicon  
layer to III-V layer



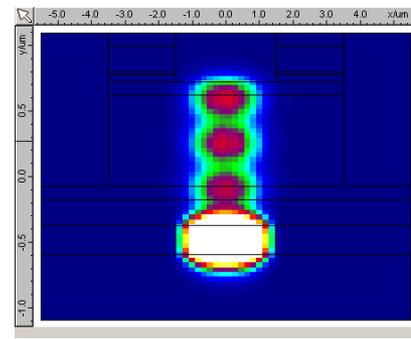
# Increase high-speed performance

- Optimize trade-off RC-limit and transit-limit
  - Find optimum absorption layer thickness  $d$

Thin InGaAs  
- Coupling the 0th order

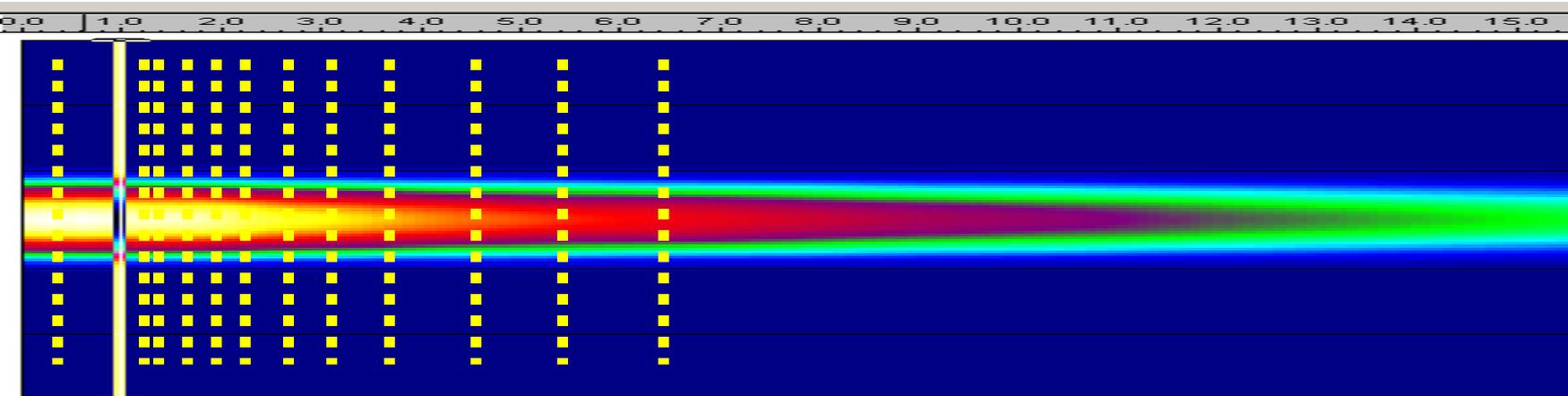
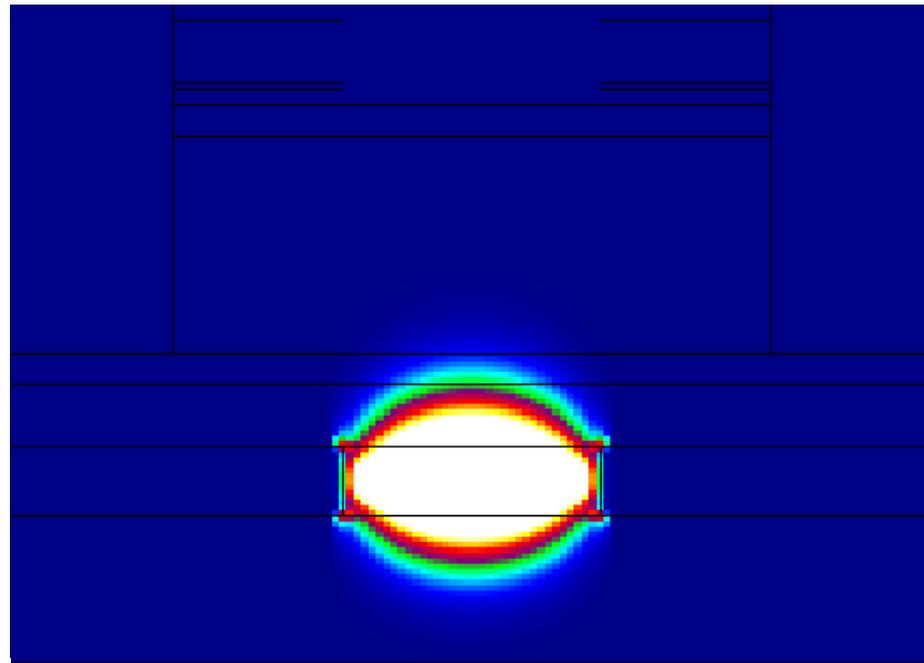


Thick InGaAs  
- Coupling to 2nd order



- Optimize silicon waveguide for phase matching
  - High responsivity:
    - minimized metal contact absorption
  - Fast absorption:
    - short detector length for lower capacitance

# Example: Simulating TM detector



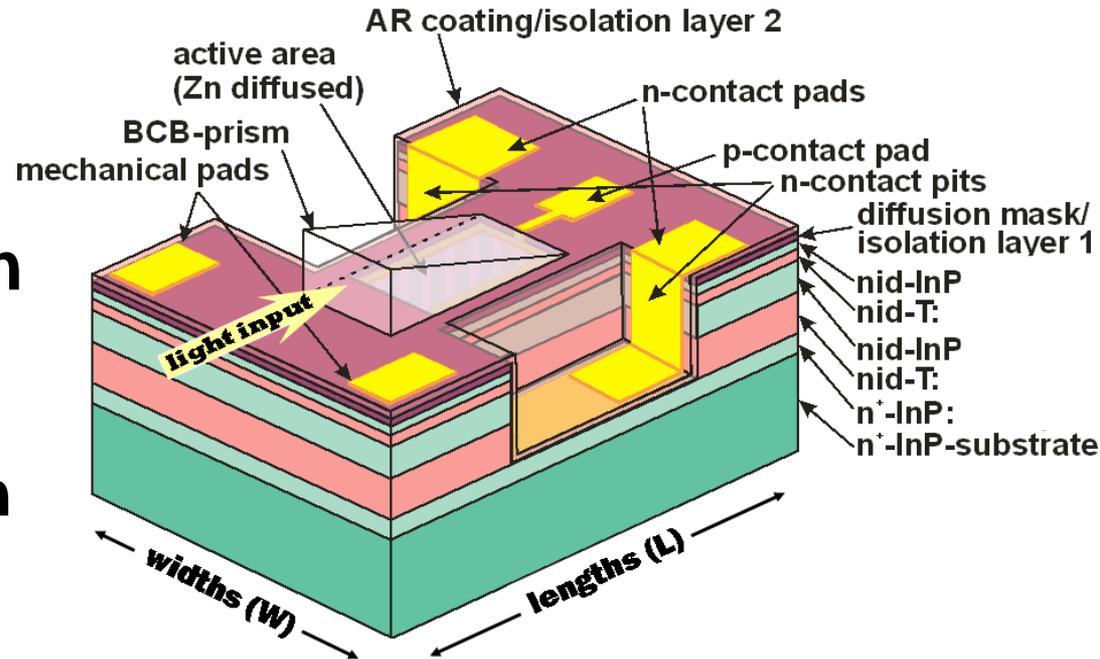
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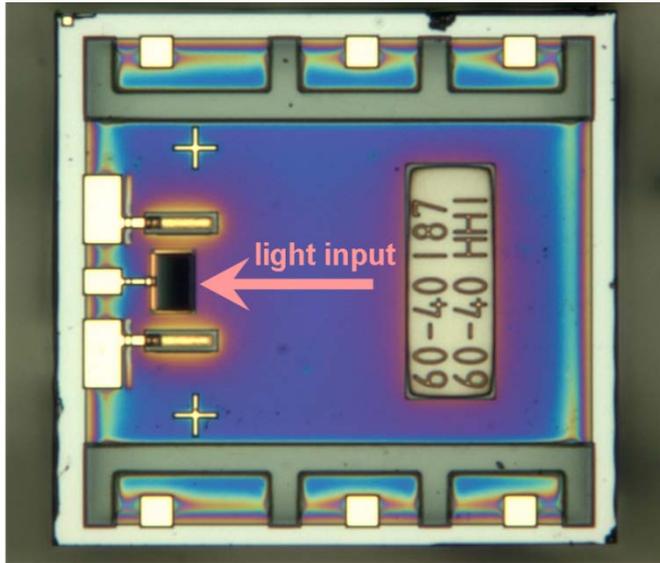
## Standard photodiode processing sequence

### + BCB prism fabrication as add-on:

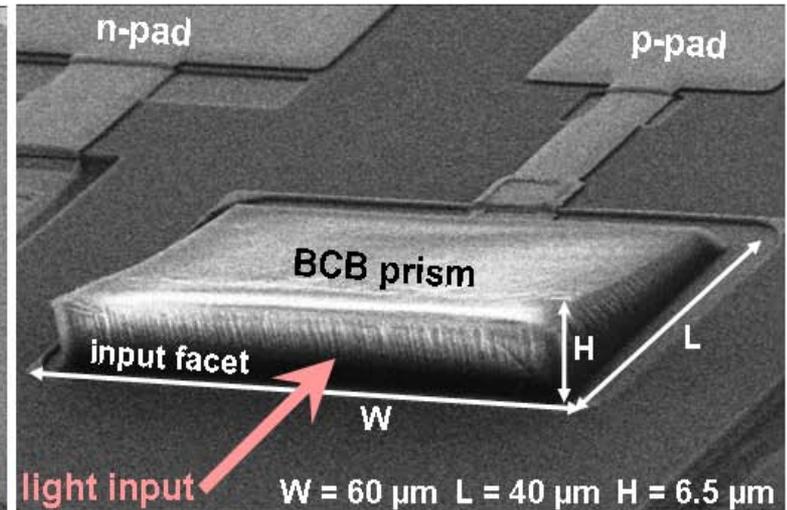
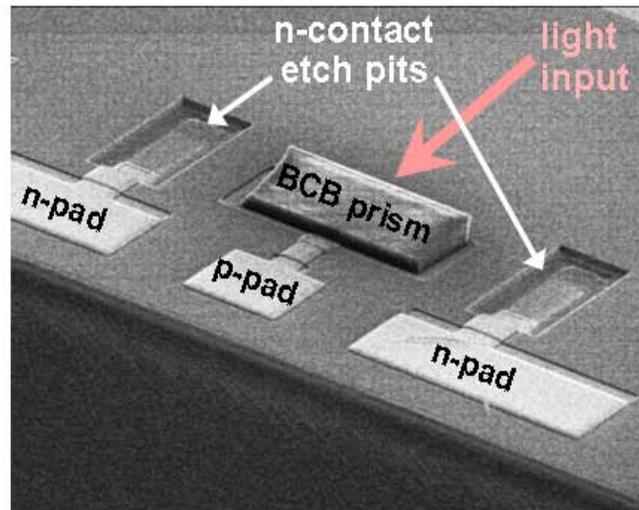
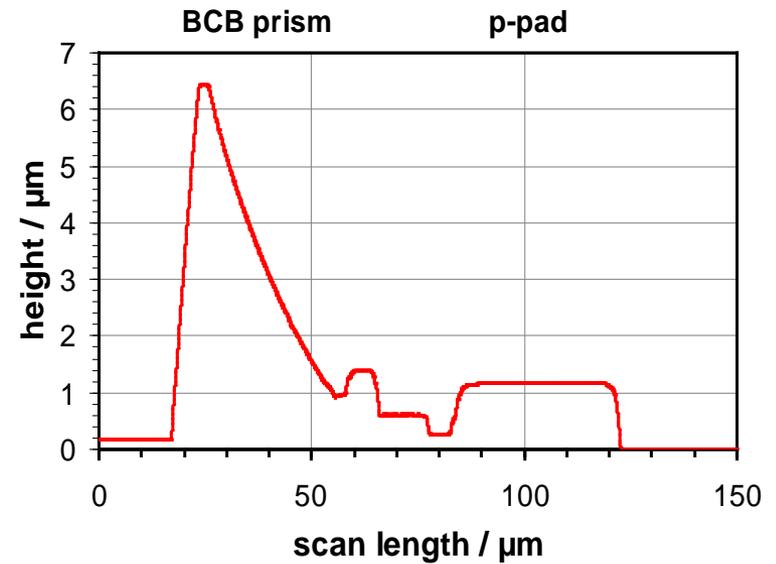
- ❶ BCB layer deposition and curing
- ❷ Lithography to produce a tapered resist mask (providing sliding mask technique)
- ❸ Relief transfer into BCB layer by RIE process ( $O_2$  containing plasma)

➔ Advantage: “custom-made” prism shapes available



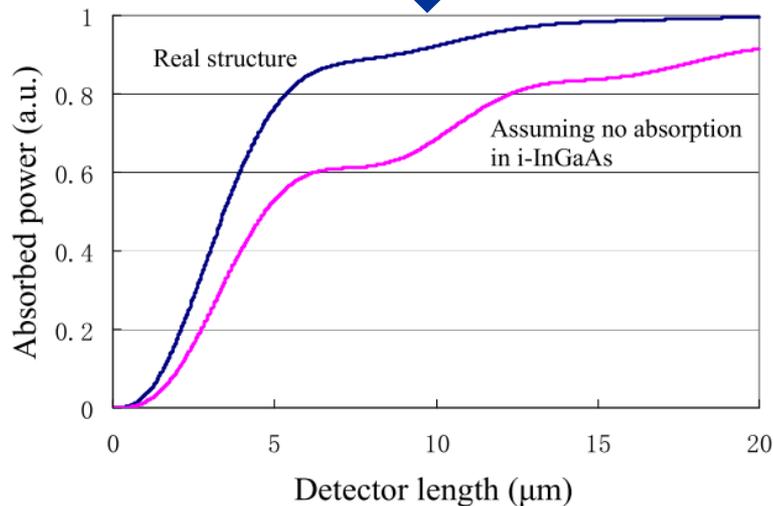
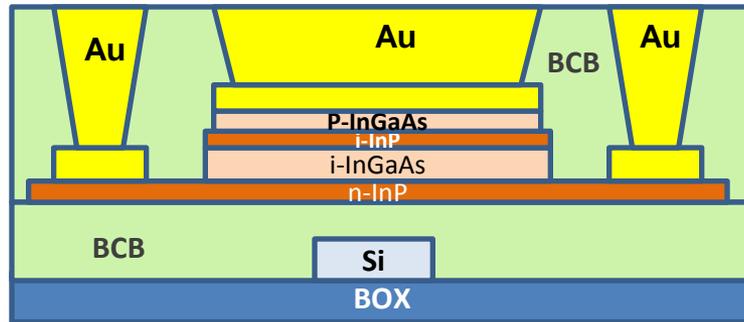


Chip  
footprint:  
500 x 500  
 $\mu\text{m}^2$

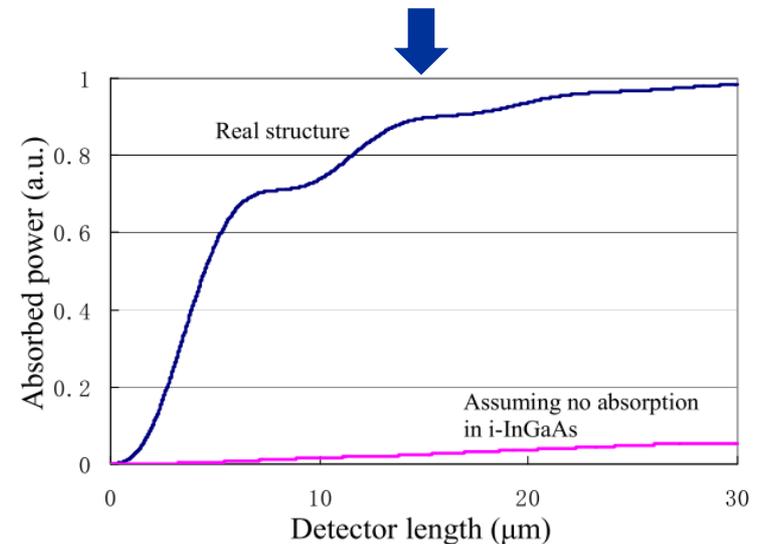
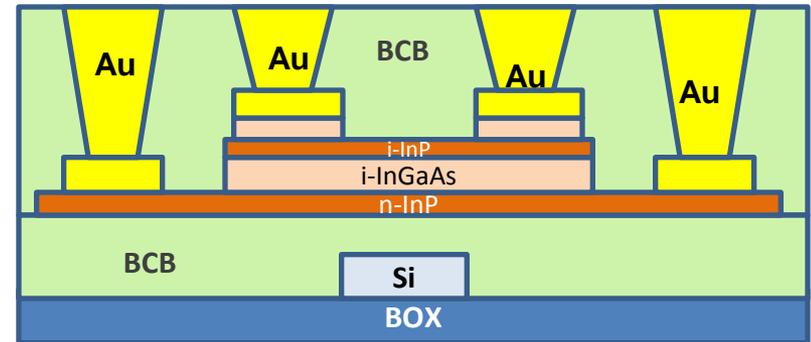


# Photodiode design evanescent coupling

## Old design



## New design: the helmet

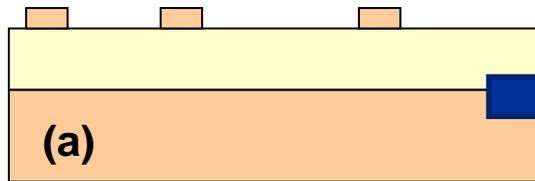


**Improvement in responsivity by minimizing absorption in contact metal and p-doped InGaAs**

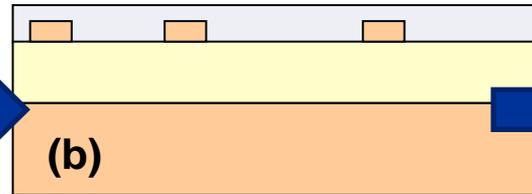
Z. Sheng, GFP, 2009

# Heterogeneous integration

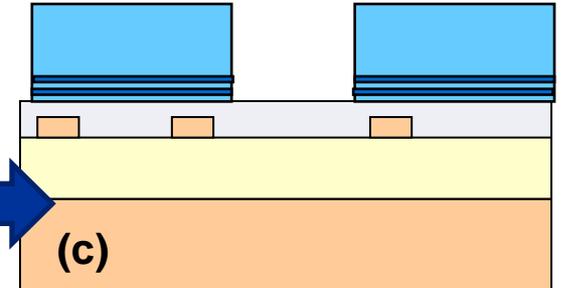
SOI-wafer



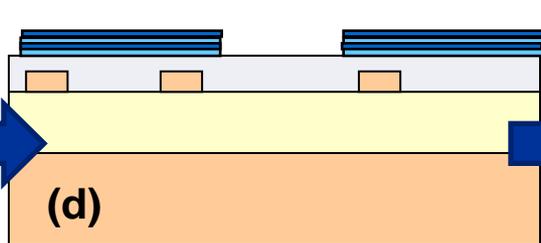
Planarization (BCB)



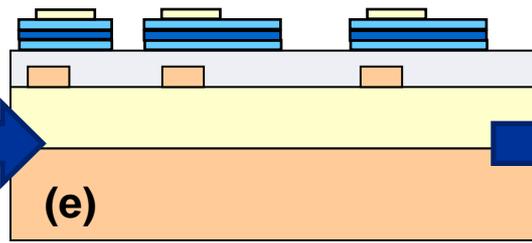
Bonding III-V die



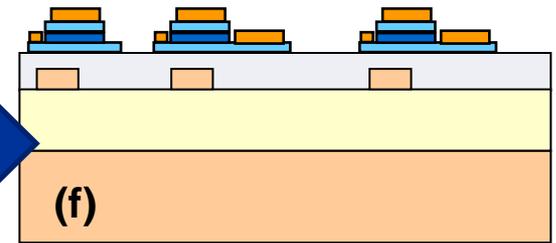
Substrate Removal



Pattern definition

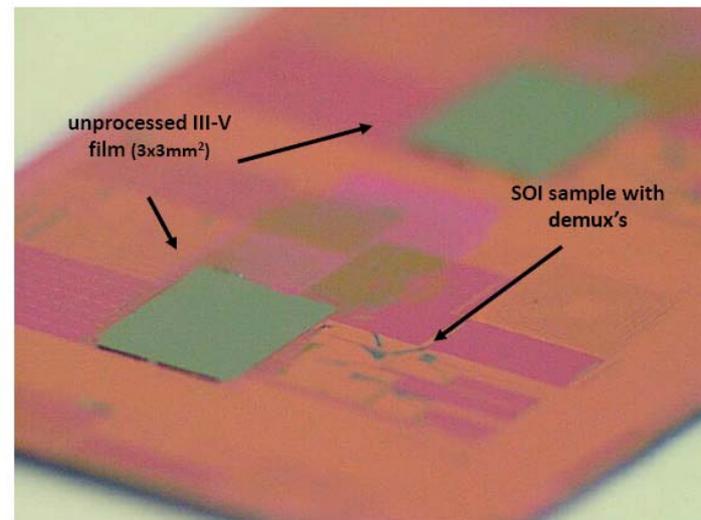


III-V processing

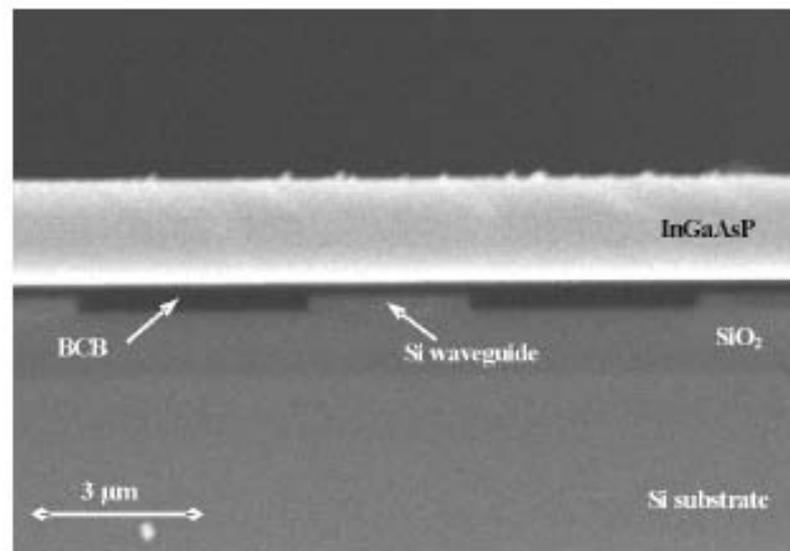


# Heterogeneous integration examples

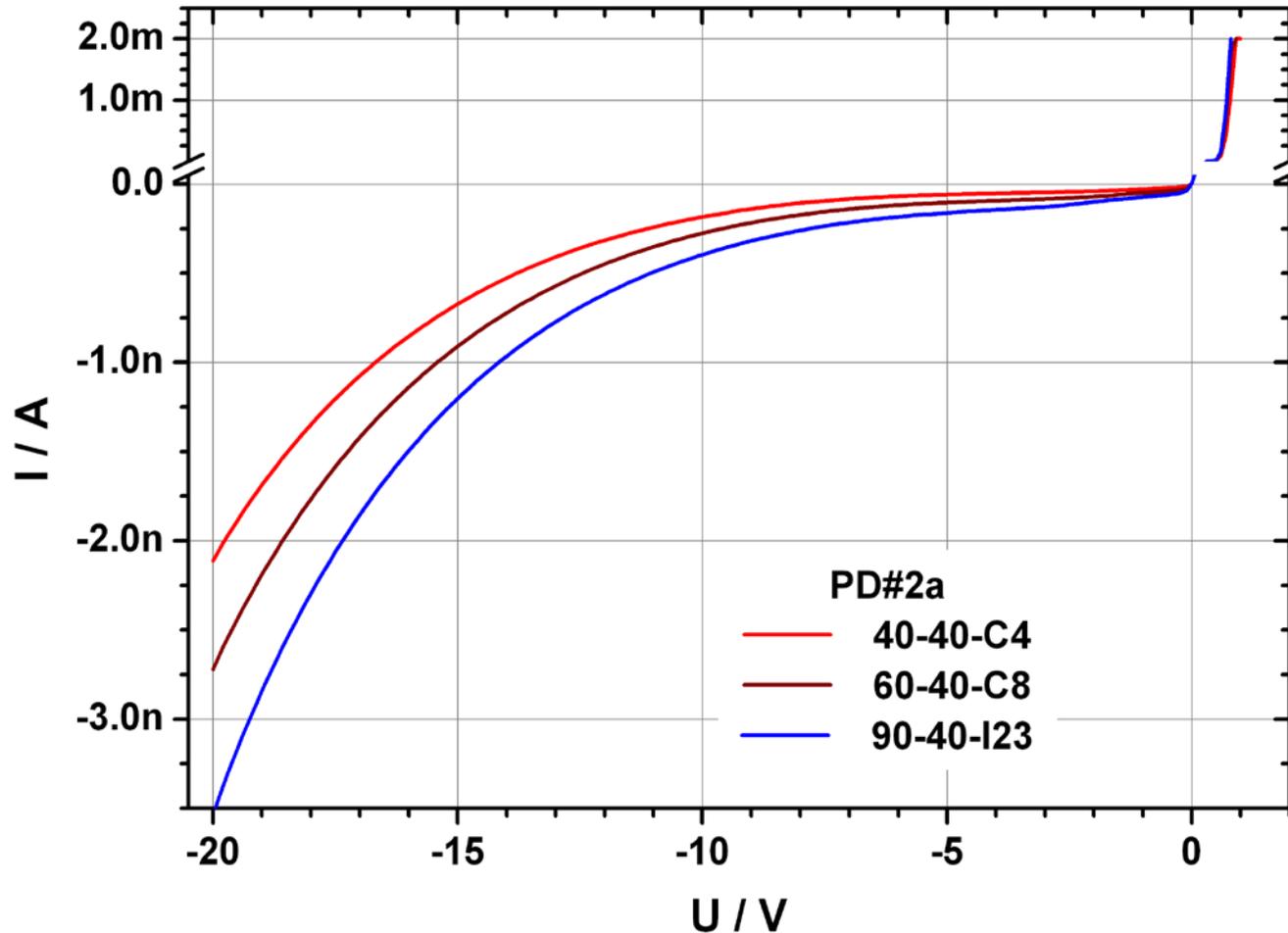
- Two unprocessed BCB bonded InP-based epitaxial layers (3 x 3 mm<sup>2</sup>) on top of an SOI substrate



- Cross-section SEM picture of a III-V film (after substrate removal) bonded on SOI using a 100 nm BCB layer



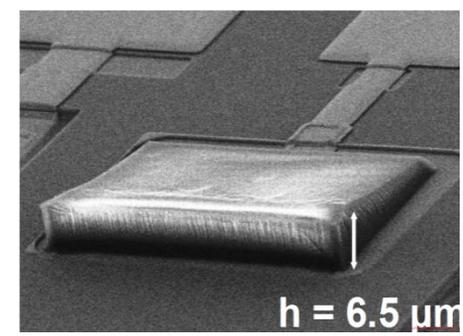
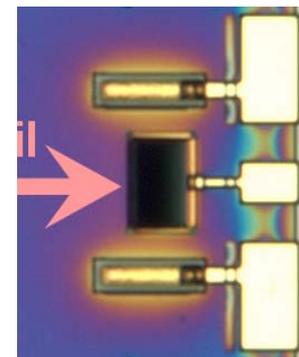
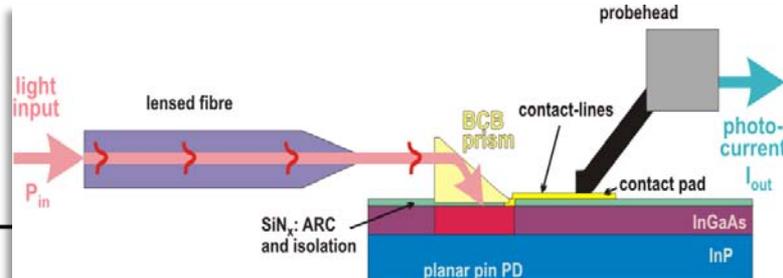
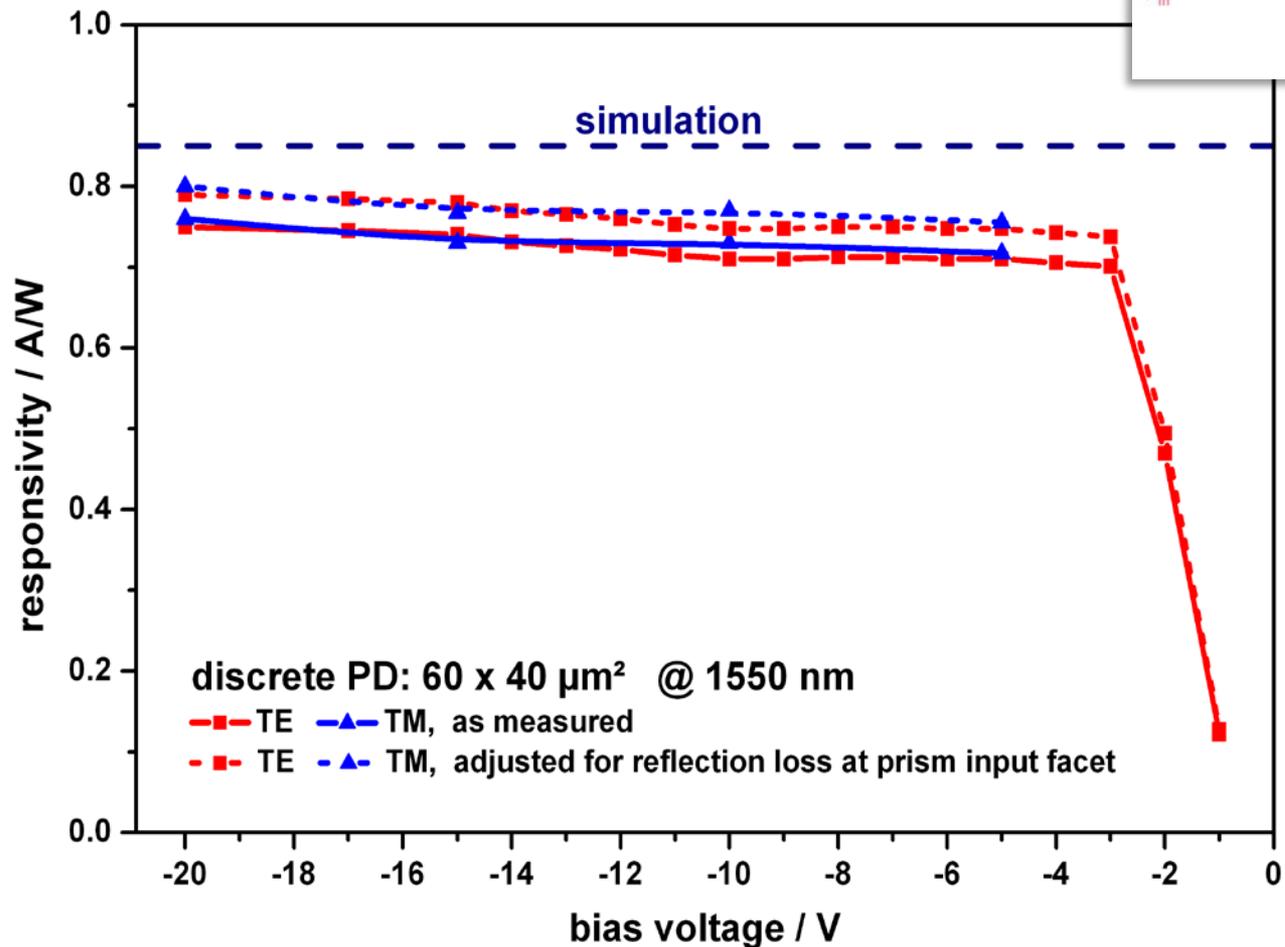
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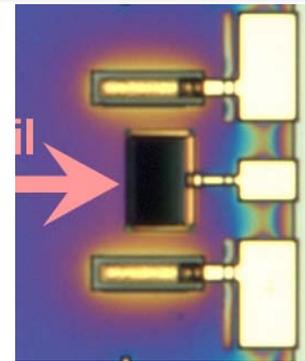
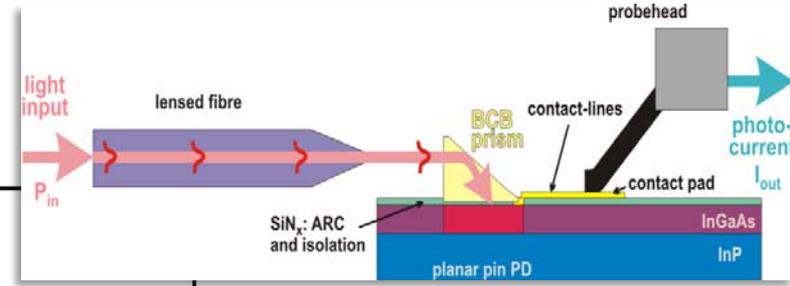
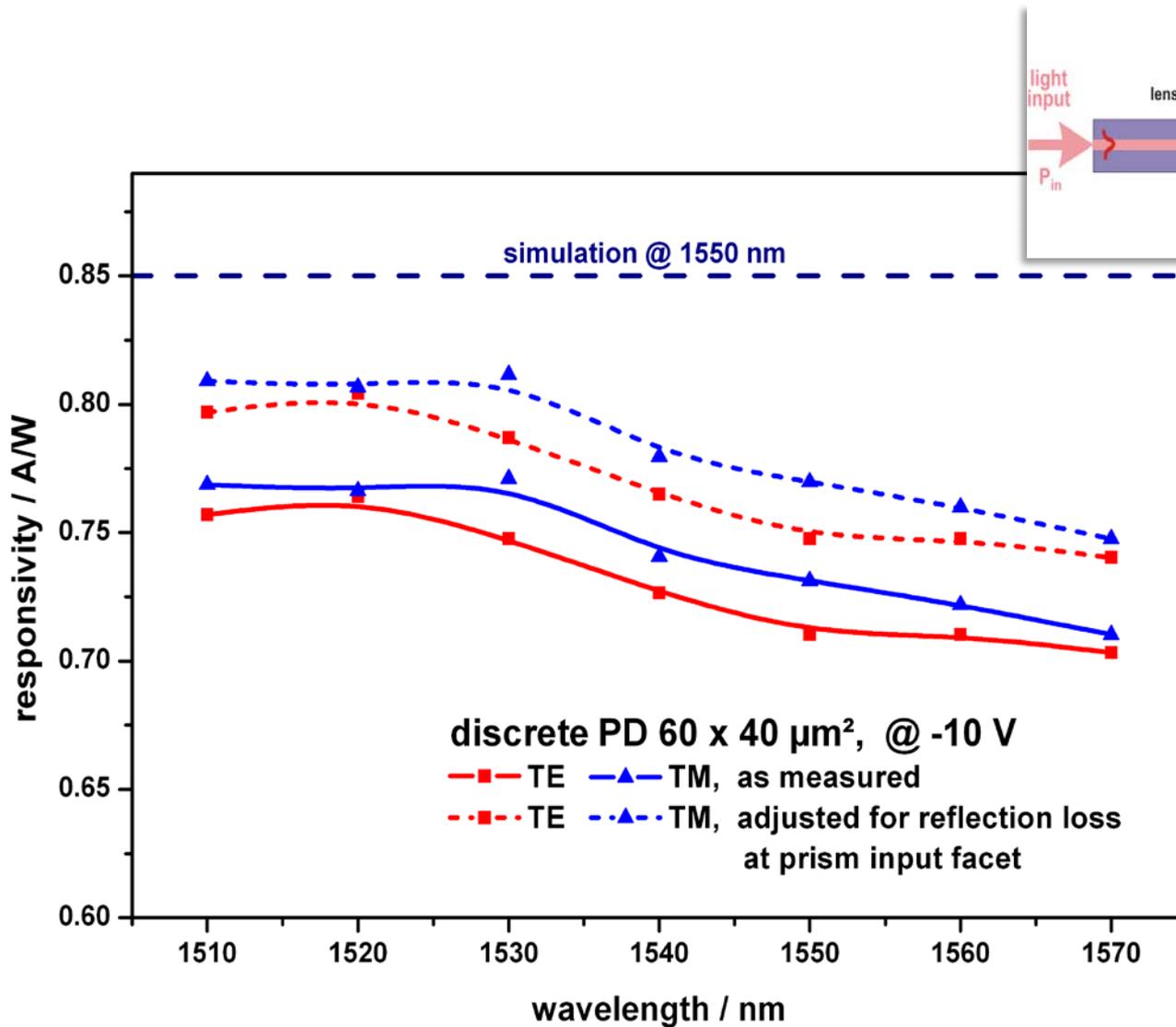


**Low dark  
currents**

**High  
breakdown  
voltages**

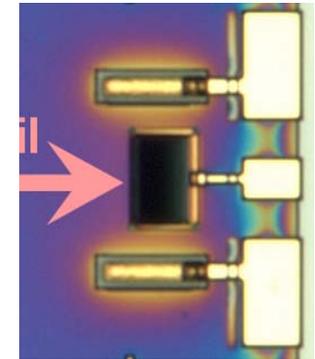
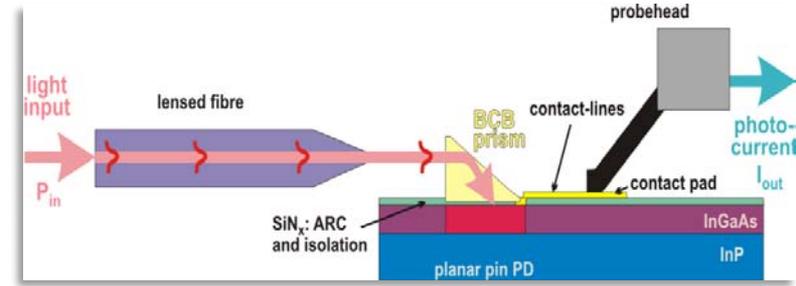
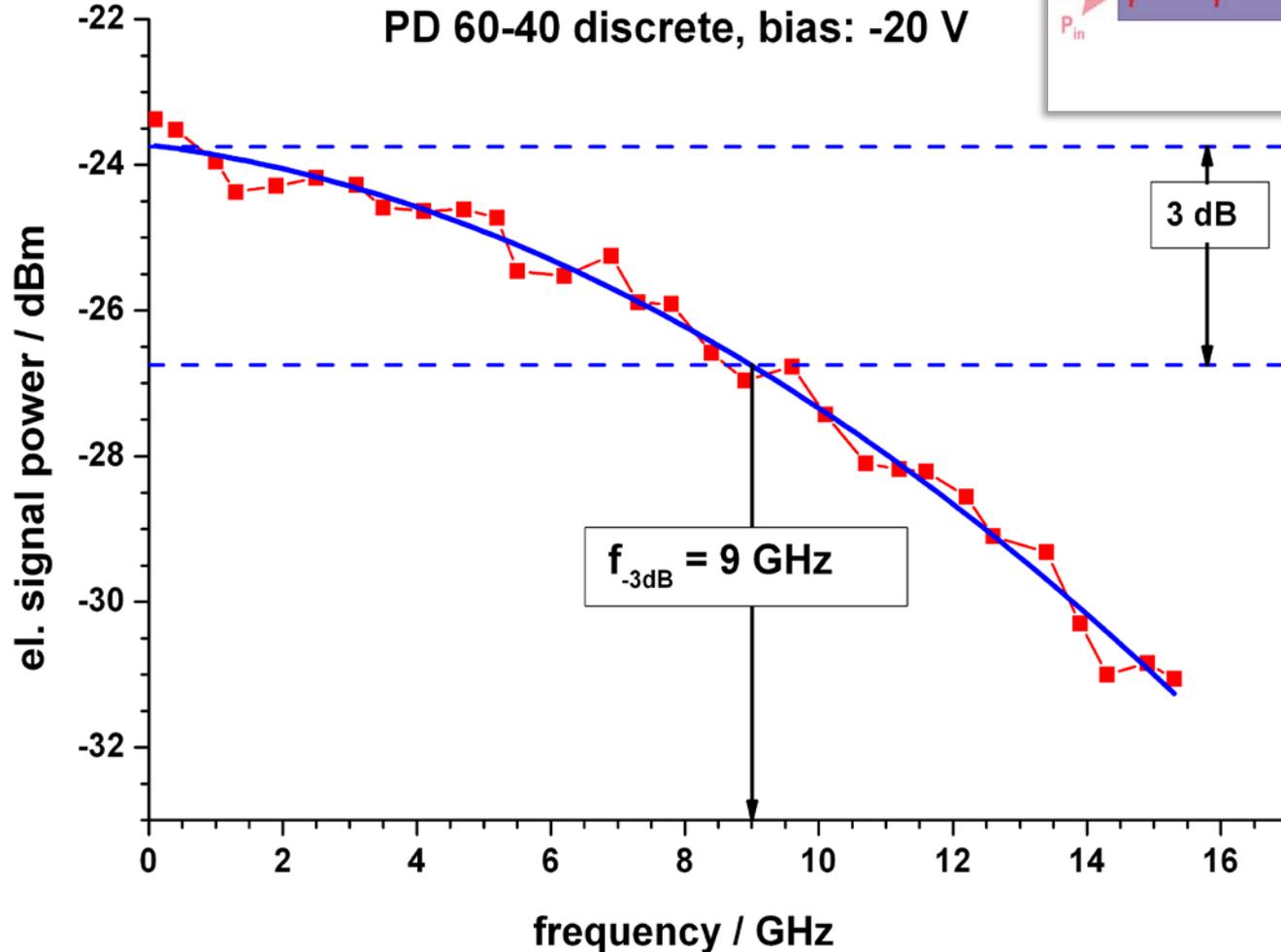
## High responsivity





**Weak dependence on wavelength and polarization**

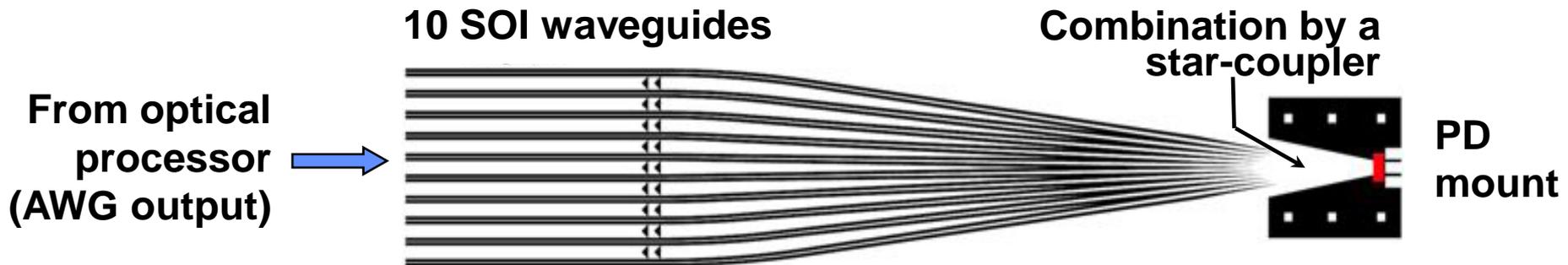
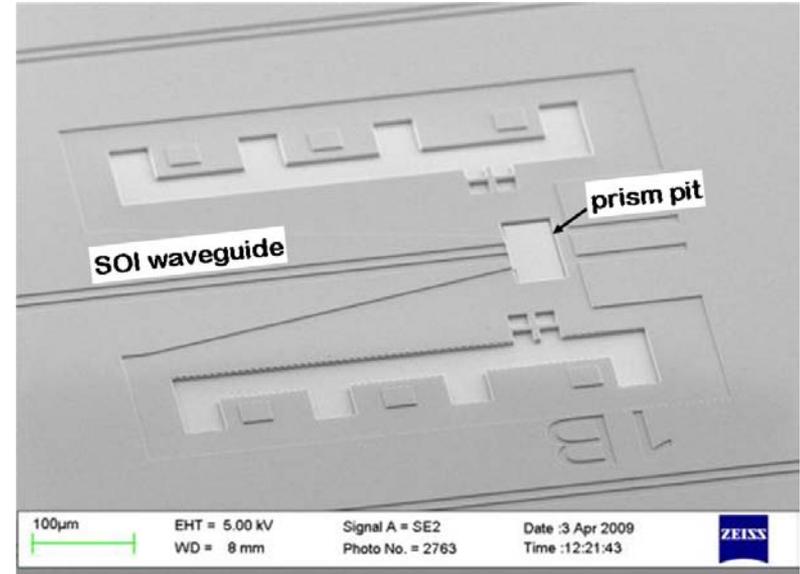
# Photodiode performance – discrete chips (4)

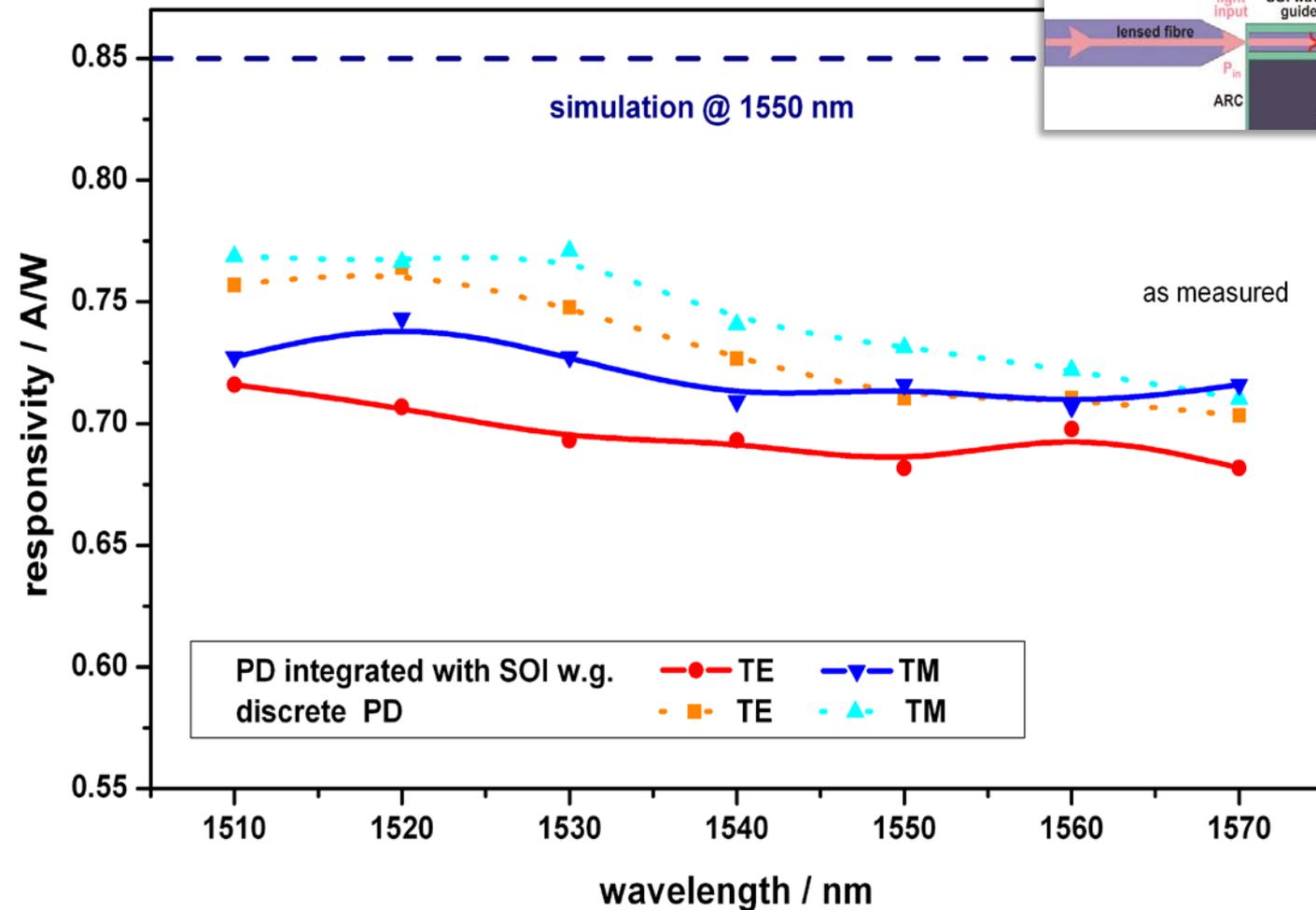
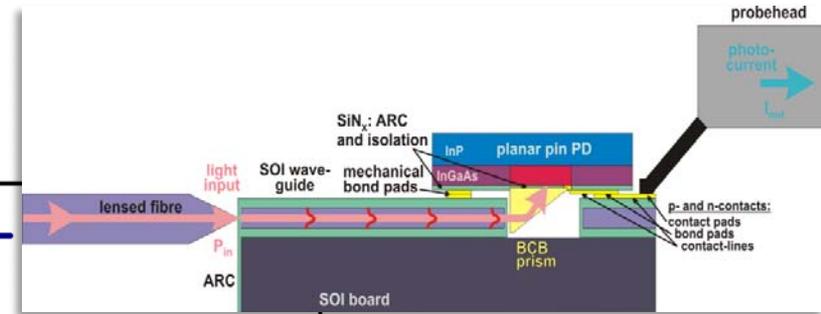


**Bandwidth  
suitable for  
10 Gb/s  
operation**

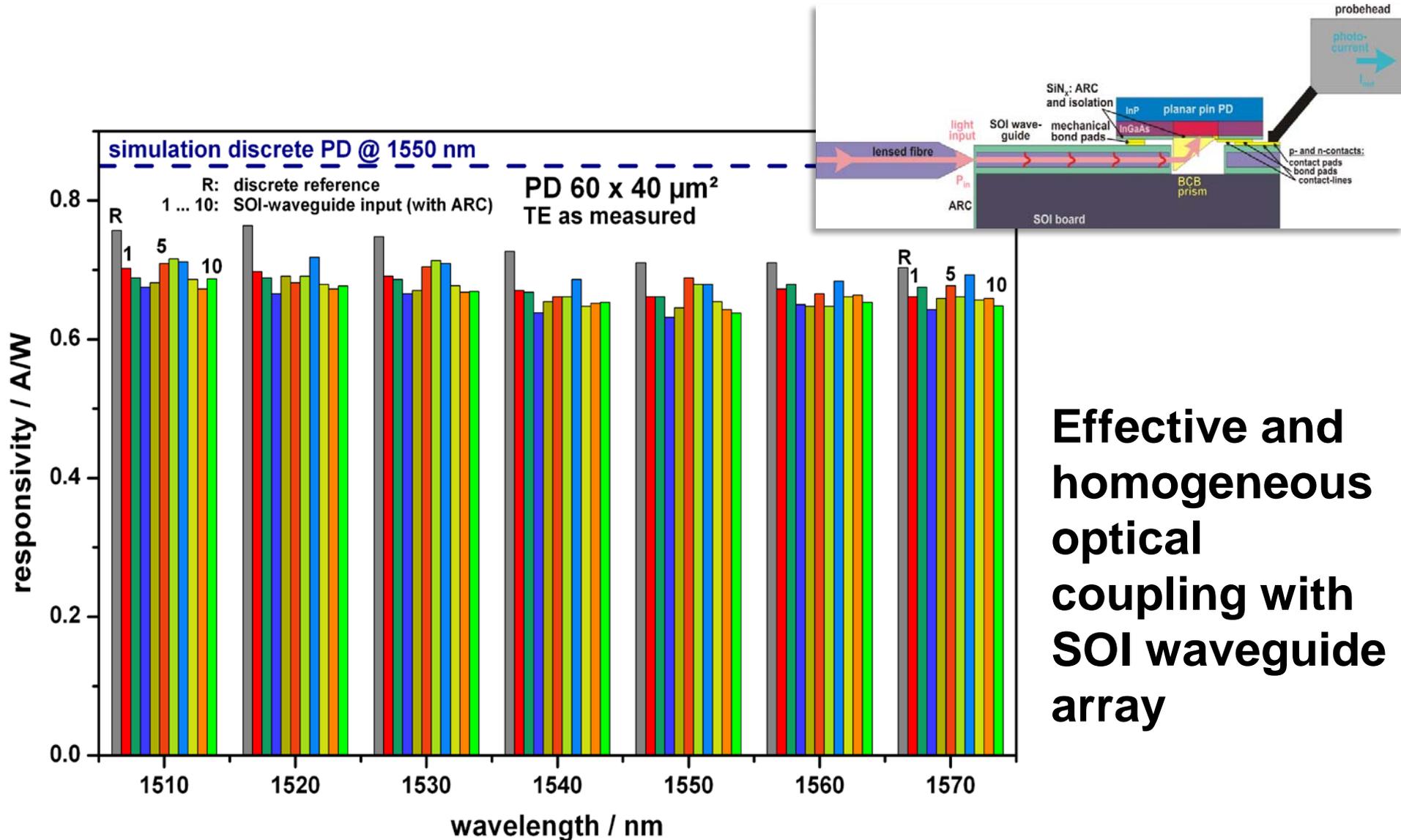
## Demands on optical coupling:

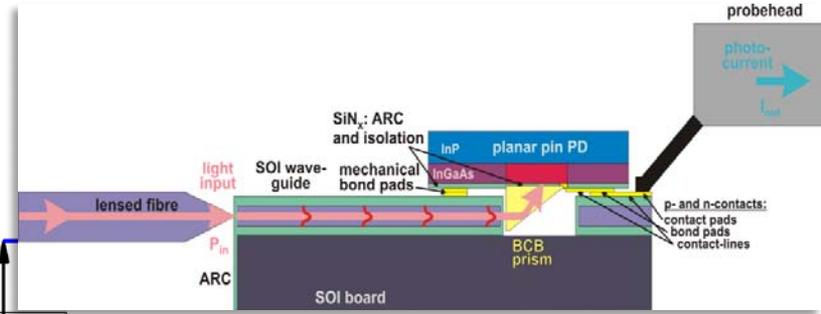
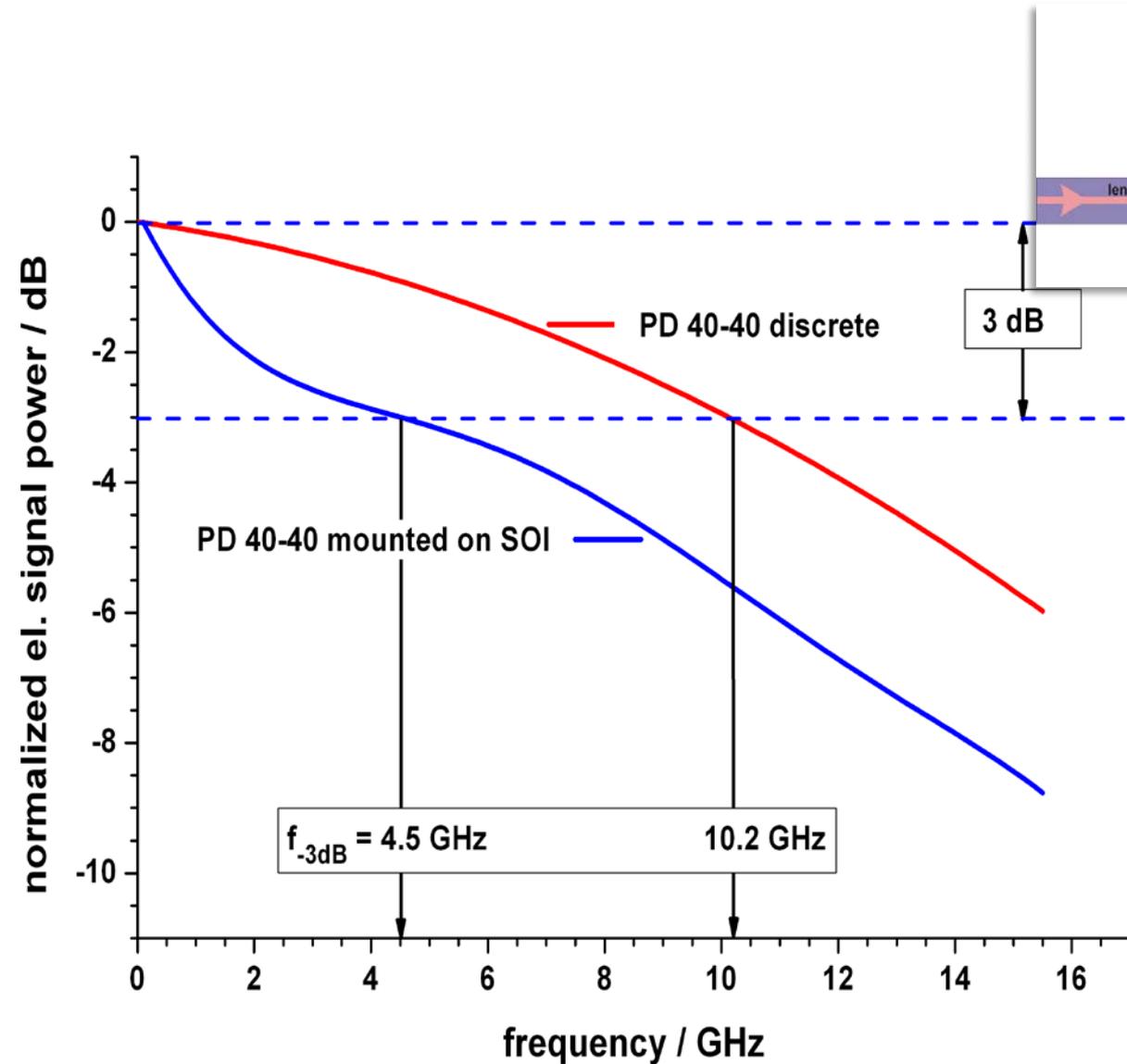
- high responsivity
  - independent on
    - wavelength
    - polarization
    - waveguide position
- high bandwidth for 10 Gb/s operation





**Weak dependence on wavelength and polarization**

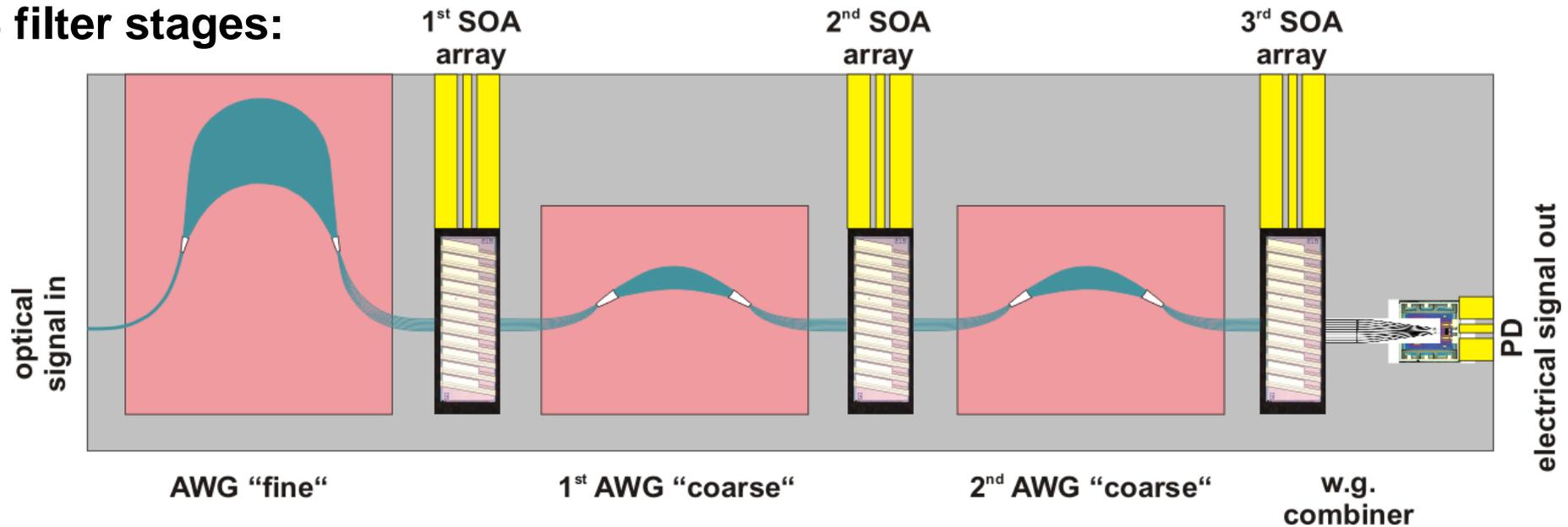




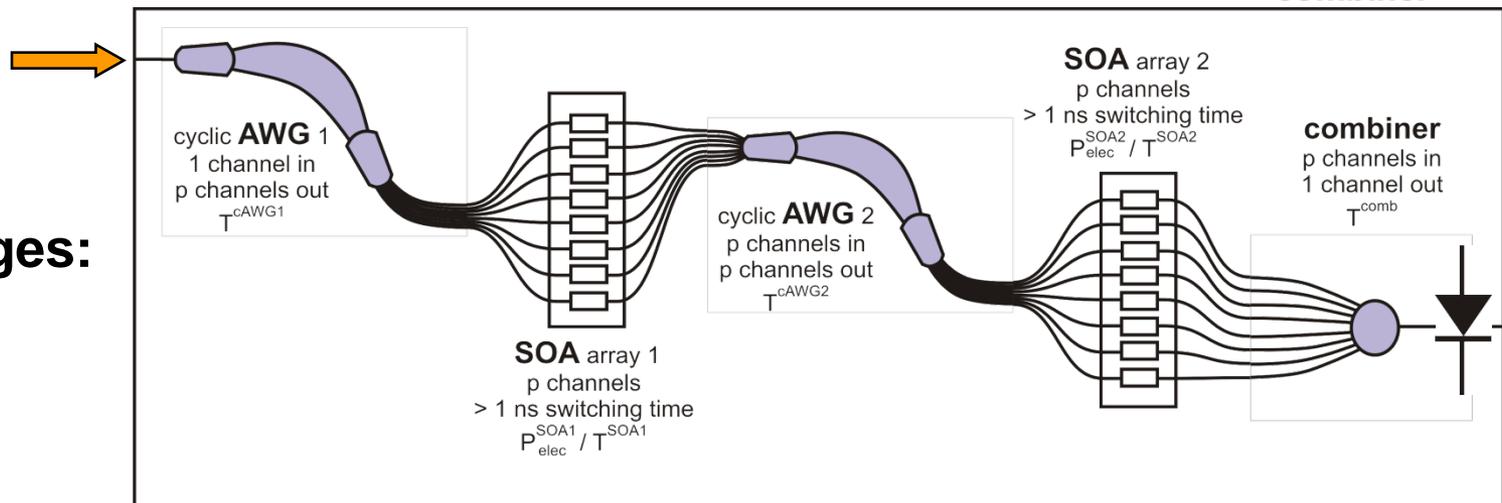
**Degradation of bandwidth due to connection via RF line on low resistivity SOI**

# OTUS channel wavelength filter

## 3 filter stages:



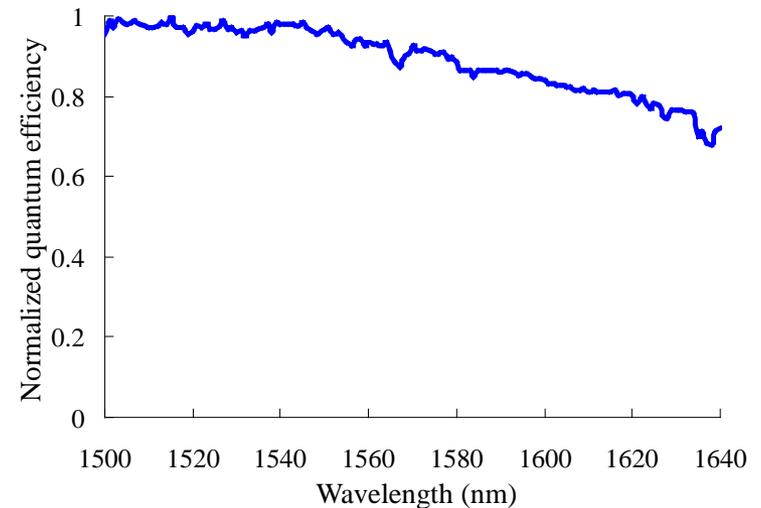
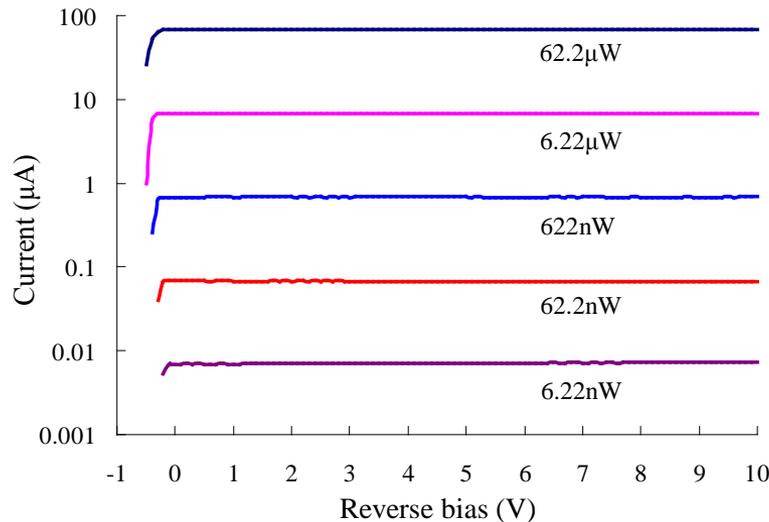
## 2 filter stages:



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- **Performance**
  - Prism PDs, discrete and integrated (for OTUS)
  - Heterogeneously integrated PDs (for BOOM)**
- **Conclusion**

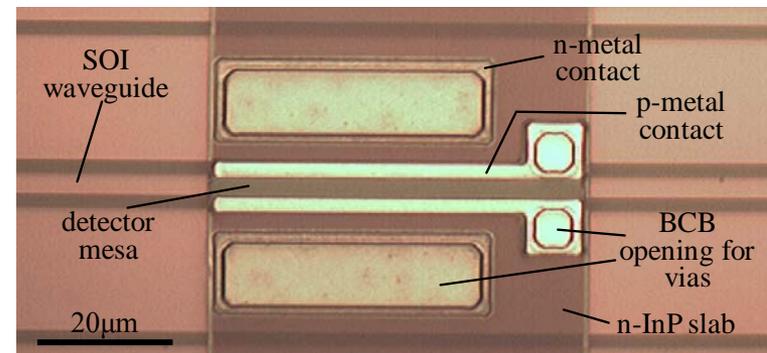
# BOOM: Photodetector results

- High responsivity (1.1 A/W @ 1550 nm or 88 % quantum efficiency)
- Covering the whole S, C and L communication band
- Very low dark current 10 pA (needs very low bias voltage)



Top view (before final metallization)

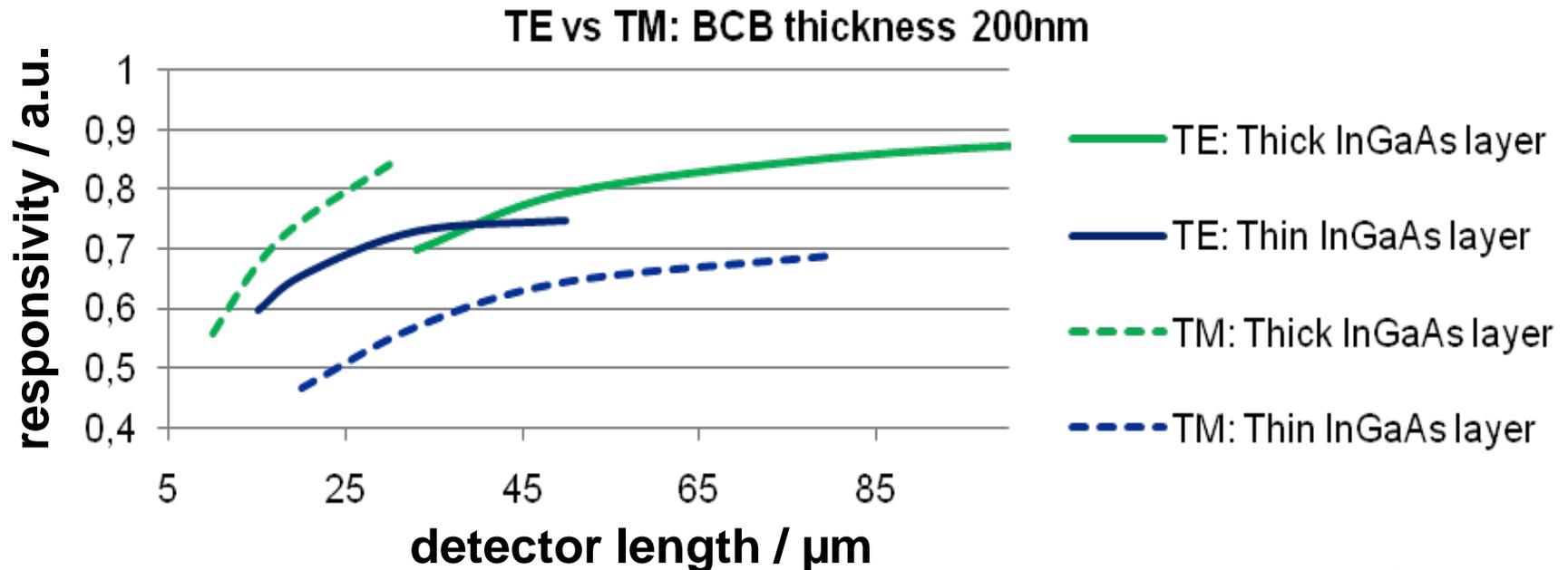
Z. Sheng, OpEx, vol 18(2), 2010



# Increase high-speed performance

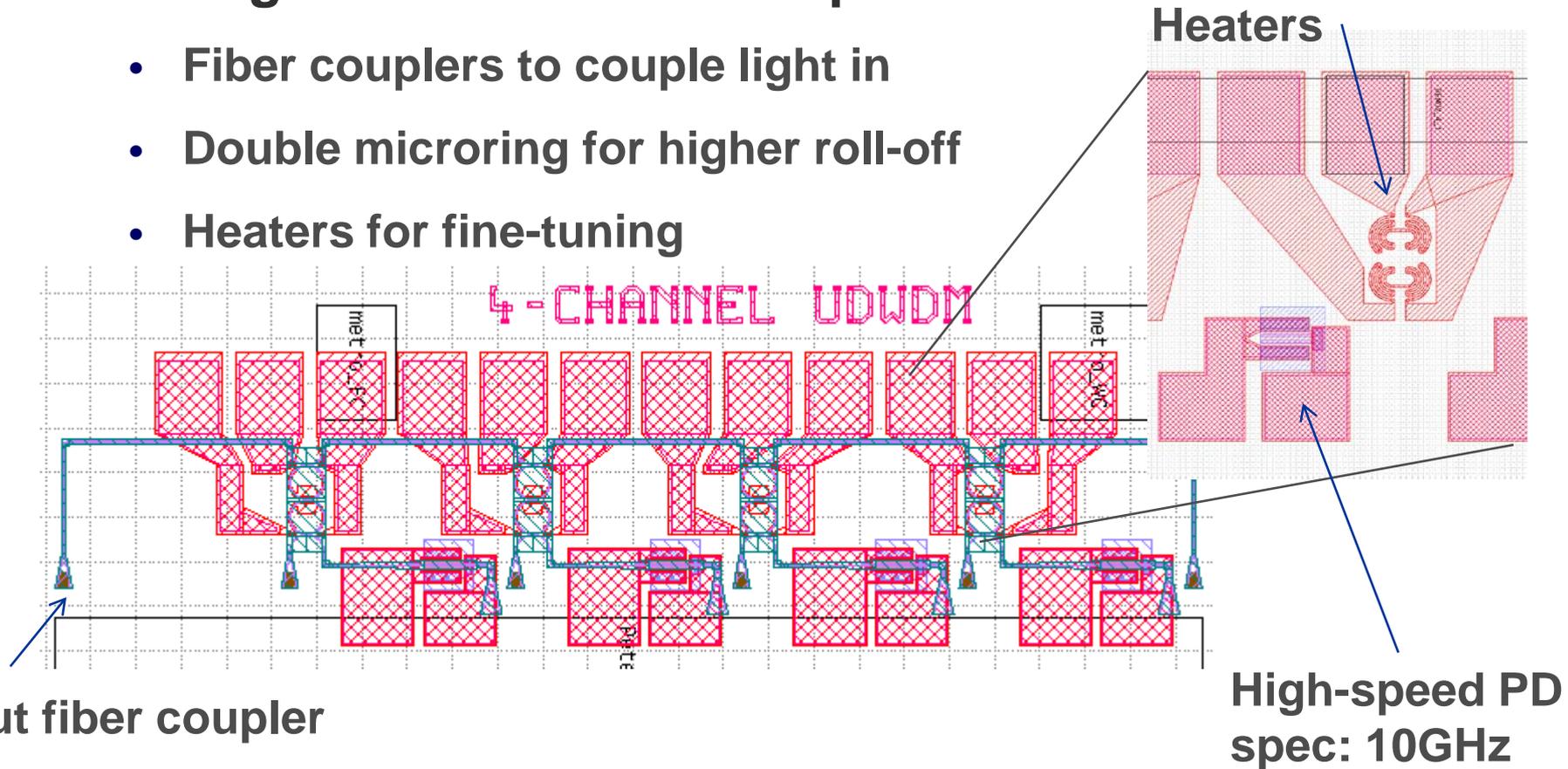
## Performance is polarization dependent

- Thin InGaAs: TE higher responsivity & faster power transfer
- Thick InGaAs:
  - TM has a faster power transfer
  - Both polarizations have higher responsivity



# BOOM: UDWDM Demultiplexer

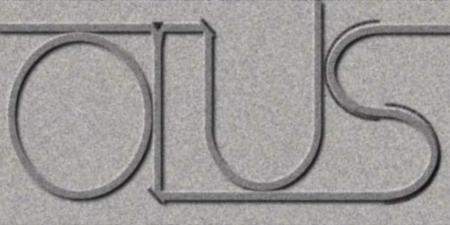
- Design: 4-channel demultiplexer
  - Fiber couplers to couple light in
  - Double microring for higher roll-off
  - Heaters for fine-tuning



- Fabrication underway

- **Successful integration of InP based photodiodes with SOI waveguides via two approaches:  
prism coupling and evanescent coupling**
- **Prism coupling via a BCB prism as add-on on standard photodiode structure:  
effective, easy to fabricate.**
- **Evanescent coupling via InGaAs dies, heterogeneously integrated on top of SOI “nano” waveguides:  
effective, more sophisticated design and technology**
- **Both approaches show high responsivity with low dependence on wavelength, suitable for 10 Gb/s operation**

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**Terabit-on-chip:**

*Micro- and Nano-scale silicon photonic integrated components and sub-systems enabling Tb/s-capacity, scalable and fully integrated photonic routers*



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